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SENT BY: WILSON & HAM;

9252490111;

DEC (23-95 208545PM;

PAGE 1

AMENDMENT TRANSMITTAL LETTER Under Small Entity Status					Attorney Docket No: INK-002	
Application Serial Number: 10/829,593		Filing Date: 04/21/2004		Examiner: Rachuba, Maurina T.		Group Art Unit: 3723
Invention: APPARATUS AND METHOD FOR POLISHING SEMICONDUCTOR WAFERS USING ONE OR MORE POLISHING SURFACES						
TO THE COMMISSIONER OF PATENTS AND TRADEMARKS: Transmitted herewith is an amendment in the above-identified application. The fee has been calculated as shown below.						
CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENOMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	NO. OF EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	113	MINUS	. 113	0	\$25	\$ 0.00
INDEP. CLAIMS	11	MINUS	11	0	\$100	\$ 0.00
Petition is hereby made under 37 CFR 1.136(a) to extend the time for response to the Office Action to and through, comprising an extension of the shortened statutory period of: one month (\$60) three months (\$510) two months (\$225) four months (\$795)						
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT \$ 0.00						
Small entity status of this application under 37 CFR 1.9 and 1.27 has been established by a verified statement previously submitted.						
A verified statement to establish small entity status under 37 CFR 1.9 and 1.27 is enclosed.						
A check in the amount of \$ is attached.						
Charge \$ to Deposit Account						
X No additional fee is required.						
12/22/2005 Date Thomas H. Ham Reg. No. 43,654						
Patent and Tradema	cert this paper (along with ark Office facsimile n s: 6 (including TRA Thomas H. F	h any paper umber (571 NSMITTA) 273-8300 on Dece	attached or end	C.F.R. 1.8 closed) is being facsi	mile transmitted to the

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Attorney Docket No. INK-002

PATENT APPLICATION

DEC 2 2 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): In Kwon Jeong

Group Art Unit: 3723

Serial No. 10/829,593

Confirmation No. 6718

Filed: April 21, 2004

Examiner: Rachuba, Maurina T.

APPARATUS AND METHOD FOR POLISHING SEMICONDUCTOR

WAFERS USING ONE OR MORE POLISHING SURFACES

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Sir/Madam:

In response to the Office Action mailed on September 29, 2005, please consider the following Remarks, which begin on page 2 of this paper.

CERTIFICATE OF TRANSMISSION UNDER 37 C.F.R. 1.8

Thereby certify that this paper (along with any paper referred to as being attached or enclosed) is being facsimile transmitted to the Patent and Trademark Office facsimile number (571) 273-8300 on December 22, 2005.

Number of Pages: 6 (including TRANSMITTAL LETTER)

Typed Name: Thomas H. Hum